Amendments to the Claims:

The following listing of claims will replace all prior versions, and listings, of claims in the application:

1. (Previously Presented) A micro-optical device having an aligned waveguide switch, comprising:

a stationary input part with a plurality of input waveguides;

a stationary output part with a plurality of output waveguides;

a movable part with a plurality of switching waveguides, the movable part being movable relative to the stationary input and output parts; and

at least one stop block that limits movement of the movable part to align at least one of the switching waveguides with at least one of the input waveguides and at least one of the output waveguides, wherein movement of the movable part is substantially transverse.

2. (Previously Presented) The device of claim 1, wherein the stationary input part, the stationary output part and the movable part are formed of a single-crystal-silicon layer of the device.

3. (Previously Presented) The device of claim 2, wherein the at least one stop block is formed on a stationary part of the device.

4. (Original) The device of claim 2, wherein the at least one stop block comprises a polysilicon layer of the device.

5. (Original) The device of claim 4, further comprising at least one polysilicon bumper connected to the movable part.

6. (Original) The device of claim 1, wherein the at least one stop block comprises a polysilicon layer of the device.

7. (Original) The device of claim 6, further comprising at least one polysilicon bumper connected to the movable part.

8. (Currently Amended) A method for fabricating a micro-optical device having an aligned waveguide switch, comprising:

forming a stationary input part, a stationary output part and a movable part in a structural layer;

forming a plurality of waveguides in the stationary input part, the stationary output part and the movable part; and

forming at least one stop block that limits movement of the movable part to align at least one of the waveguides of the movable part with at least one of the waveguides of the stationary input and output parts, wherein movement of the movable part is substantially transverse.

9. (Original) The method of claim 8, wherein forming the plurality of waveguides comprises defining a set of offsets between the waveguides of the movable part and the waveguides of the stationary input and output parts, and

wherein forming the at least one stop block comprises defining the at least one stop block with the set of offsets.

10. (Original) The method of claim 9, wherein forming the at least one stop block further comprises defining at least one edge of the movable part with the set of offsets.

11. (Original) The method of claim 9, wherein forming the at least one stop block further comprises defining at least one bumper connected to the movable part with the set of offsets.

12. (Previously Presented) The method of claim 8, wherein the structural layer is a single-crystal-silicon layer.

13. (Previously Presented) The method of claim 12, wherein the single-crystal-silicon layer is etched to define the stationary input part, the stationary output part and the movable part.

14. (Cancelled)

15. (Previously Presented) The method of claim 1, wherein the stationary input part, the stationary output part and the movable part are part of a same layer of the device.

16. (Previously Presented) The method of claim 15, wherein the same layer is a single-crystal-silicon layer.